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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/628,626	07/28/2003	Evan R. Mapoles	58159.US	5819
60838	7590 05/03/2006	EXAMINER		
	OINT CUSTOMER	NGUYEN, TU T		
C/O LUEDEKA, NEELY & GRAHAM, P.C. P.O. BOX 1871			ART UNIT	PAPER NUMBER
KNOXVILLI	E, TN 37901		2877	

DATE MAILED: 05/03/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary		Application No.	Applicant(s)			
		10/628,626 MAPOLES ET AL.				
		Examiner	Art Unit			
		Tu T. Nguyen	2877			
Period fo	The MAILING DATE of this communication a or Reply	ppears on the cover sheet v	vith the correspondence address			
WHI0 - Extended after - If NO - Failter - Any	HORTENED STATUTORY PERIOD FOR REP CHEVER IS LONGER, FROM THE MAILING ensions of time may be available under the provisions of 37 CFR or SIX (6) MONTHS from the mailing date of this communication. O period for reply is specified above, the maximum statutory period ure to reply within the set or extended period for reply will, by staturely received by the Office later than three months after the mained patent term adjustment. See 37 CFR 1.704(b).	DATE OF THIS COMMUN  1.136(a). In no event, however, may a  d will apply and will expire SIX (6) MC  ute, cause the application to become a	IICATION.  a reply be timely filed  DNTHS from the mailing date of this communic  ABANDONED (35 U.S.C. § 133).			
Status						
1)	Responsive to communication(s) filed on			•		
2a)[_	,—	is action is non-final.	•			
3)[	3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is					
	closed in accordance with the practice under	Ex parte Quayle, 1935 C.	D. 11, 453 O.G. 213.			
Disposit	tion of Claims					
5)□ 6)⊠ 7)□	Claim(s) 1-20 is/are pending in the application  4a) Of the above claim(s) is/are withdred claim(s) is/are allowed.  Claim(s) 1-20 is/are rejected.  Claim(s) is/are objected to.  Claim(s) are subject to restriction and	rawn from consideration.				
Applicat	tion Papers					
10)⊠	The specification is objected to by the Examination The drawing(s) filed on 28 July 2003 is/are: Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the	a)⊠ accepted or b)☐ objection is required if the drawing (s) be held in abeyonetion is required if the drawing.	ance. See 37 CFR 1.85(a). ag(s) is objected to. See 37 CFR 1.13			
Priority	under 35 U.S.C. § 119					
a	Acknowledgment is made of a claim for foreign All b) Some * c) None of:  1. Certified copies of the priority docume 2. Certified copies of the priority docume 3. Copies of the certified copies of the priority docume application from the International Bure See the attached detailed Office action for a li	nts have been received.  nts have been received in iority documents have bee eau (PCT Rule 17.2(a)).	Application No In received in this National Stage	<b>;</b>		
A441						
Attachme  1) Noti	nt(s) ice of References Cited (PTO-892)	4) Interview	v Summary (PTO-413)			
2) Not	ice of Draftsperson's Patent Drawing Review (PTO-948) rmation Disclosure Statement(s) (PTO-1449 or PTO/SB/0	Paper N	o(s)/Mail Date f Informal Patent Application (PTO-152)			

U.S. Patent and Trademark Office PTOL-326 (Rev. 7-05)

Paper No(s)/Mail Date <u>07/28/2003</u>.

6) Other: \_\_\_\_.

## **DETAILED ACTION**

## Claim Objections

Claim 10 is objected to because of the following informalities:

1) Claim 10, line 1, "the method of claim 8" should be changed to "the method of claim 9".

## Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Applicant Admitted Prior Art (Specification, pages 2-15) (AAPA hereinafter) in view of Jasper et al (6,674,510) and Finarov (6,038,029).

With respect to claims 1,9-10, AAPA disclose an integrated inspection system adapted to inspect a substrate. The inspection system comprising: a first inspection station adapted to perform a first inspection of the substrate at a first resolution and for identifying defect candidate sites (AAPA, page 2, lines 20-24), a second inspection station adapted to perform a second inspection of the defect candidate sites at a second resolution, where the second resolution is higher than the first resolution (AAPA, page 2, lines 25-28; page 3, lines 1-8).

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AAPA does not explicitly disclose the first inspection station disposed at a first known location, a second station disposed at a second known location, a controller, a substrate stage adapted to move the substrate between the first known location of the first inspection station and the second known location of the second inspection station. Jasper discloses a system for inspecting a substrate. The system comprises: a substrate stage (column 2, lines 58-62) adapted to move the substrate between the first known location of the first inspection station and the second known location of the second inspection station (column 6, lines 35-42, Jasper discloses that the stage could be used for multiple measurement stations), a controller (a position system, column 2, line 58). It would have been obvious to modify AAPA with the substrate stage and a controller taught by Jasper to facilitate the measuring.

Jasper does not explicitly disclose a stage to move the substrate under both inspection stations. Finarov discloses a stage 110 (fig 7A) for moving the substrate under different measuring systems. It would have been obvious to modify Jasper stage with the stage taught by Finarov to perform different measuring processes without transferring the substrate to reduce loss of accuracy as taught by Finarov in column 2, lines 10-25).

With respect to claims 2-3, AAPA discloses using an optical inspection system for the first station and a microscope for a second station (Specification, page 2, last paragraph and page 3, first paragraph).

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With respect to claims 4-7,11-14,18-20, the claimed microscopes would have been known. It would have been obvious to modify AAPA with different types of microscope for different measuring purposes.

With respect to claims 8,15, Jasper does not explicitly disclose the distance between the stations. However, according to fig 8, the distance between the stations 20a and 10 seems to be fixed. Further, It would have been obvious to modify Jasper by having a known distance between the stations in order to move the substrate between the stations easier.

With respect to claim 16, refer to discussion in claim 1 above for the system.

Further, AAPA discloses classifying the defects by the second system (page 2, lines 25-28).

With respect to claim 17, refer to discussion claim 1 above for the controller.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Tu T. Nguyen whose telephone number is (571) 272-2424. The examiner can normally be reached on T-F 7:30-5:30.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Gregory Toatley Jr. can be reached on (571) 272-2800 Ext. 77. The fax

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phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Tu T. Nguyen Primary Examiner Art Unit 2877

04/25/2006